

Abstract

Title: A wafer-transfer technique for a continuous membrane MEMS deformable mirror

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Summary: A continuous single crystal silicon membrane deformable mirror concept has been proposed. This concept, a sheet of optical equality single crystal silicon is transferred onto deformable membrane actuators. Thick silicon membrane, 100 mm in diameter, has been successfully transferred without using adhesives or polymers. The successive single crystal silicon membrane transfer onto a deformable membrane actuator array is under development.